

Applicant(s): Kiyoshi Mita  
SEMICONDUCTOR DEVICE AND METHOD OF  
MANUFACTURING THE SAME



FIG.1A



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S

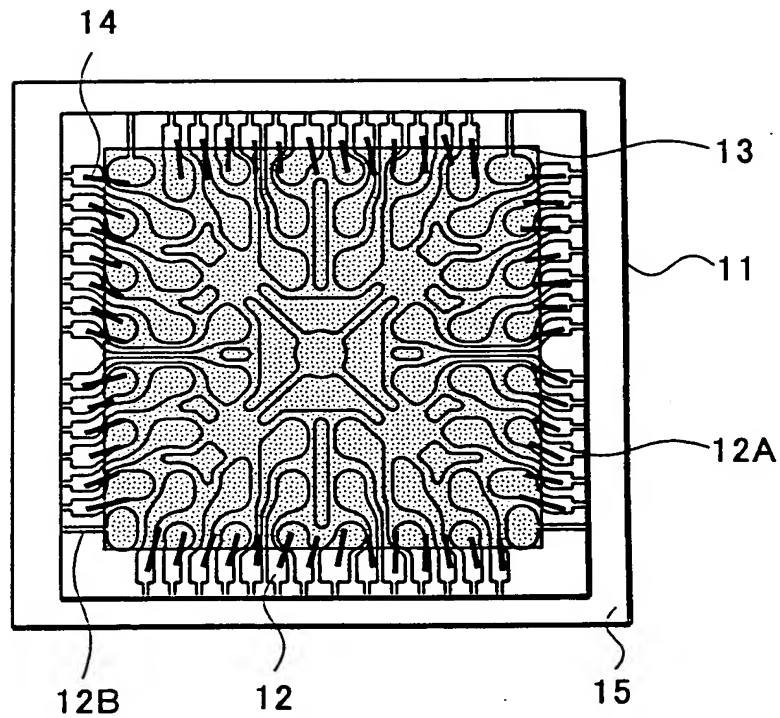


FIG.1B

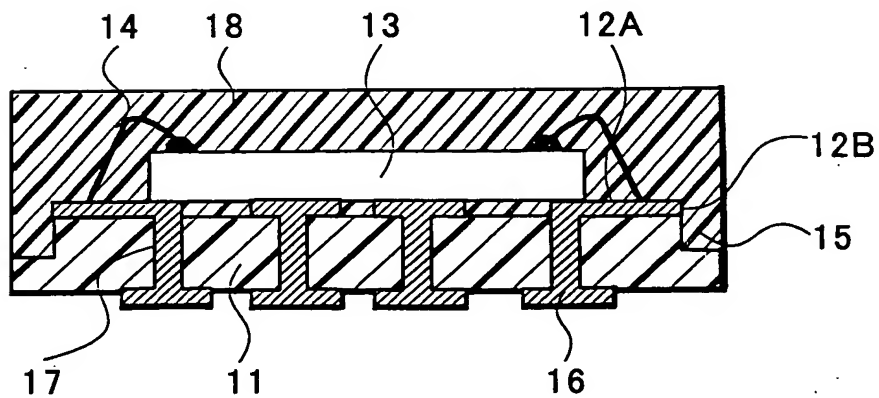


FIG.2A

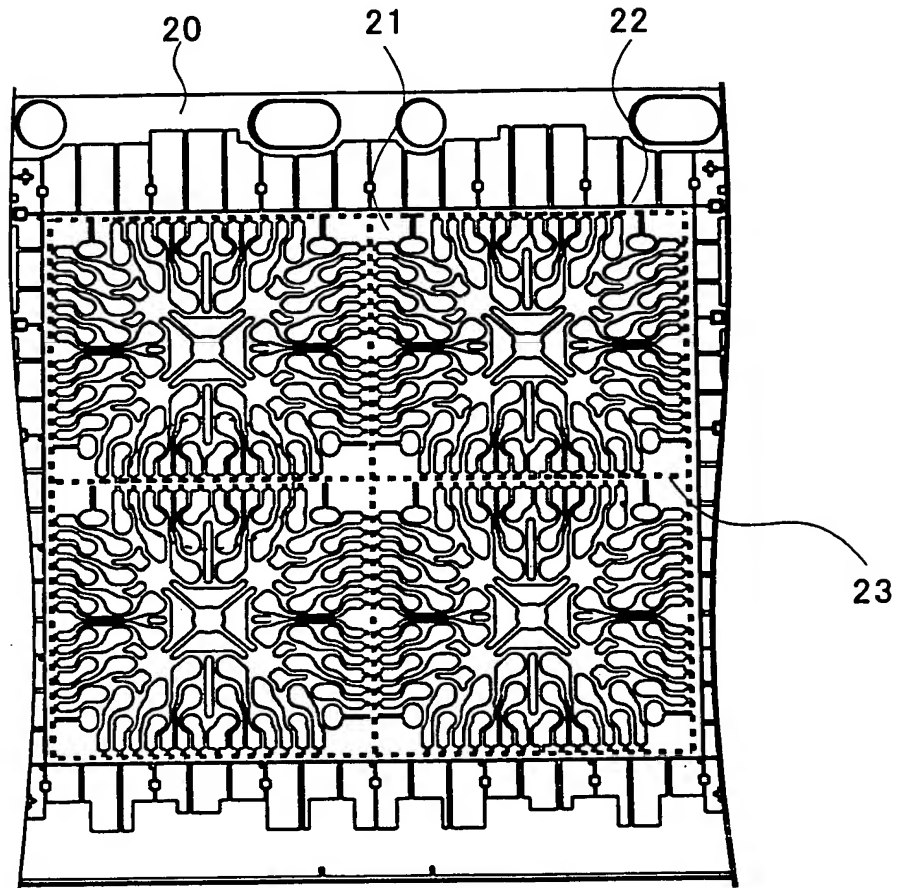


FIG.2B

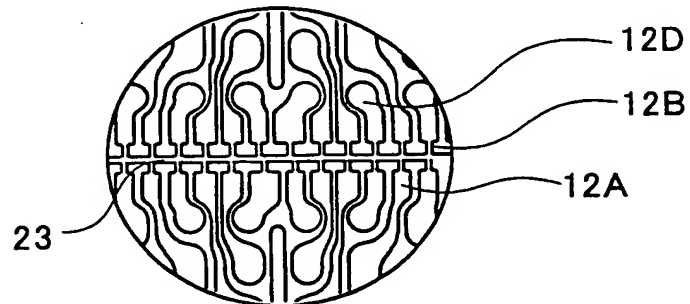


FIG.2C

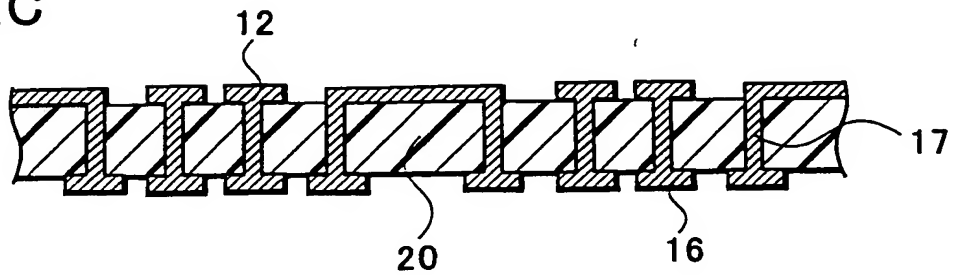


FIG. 3A

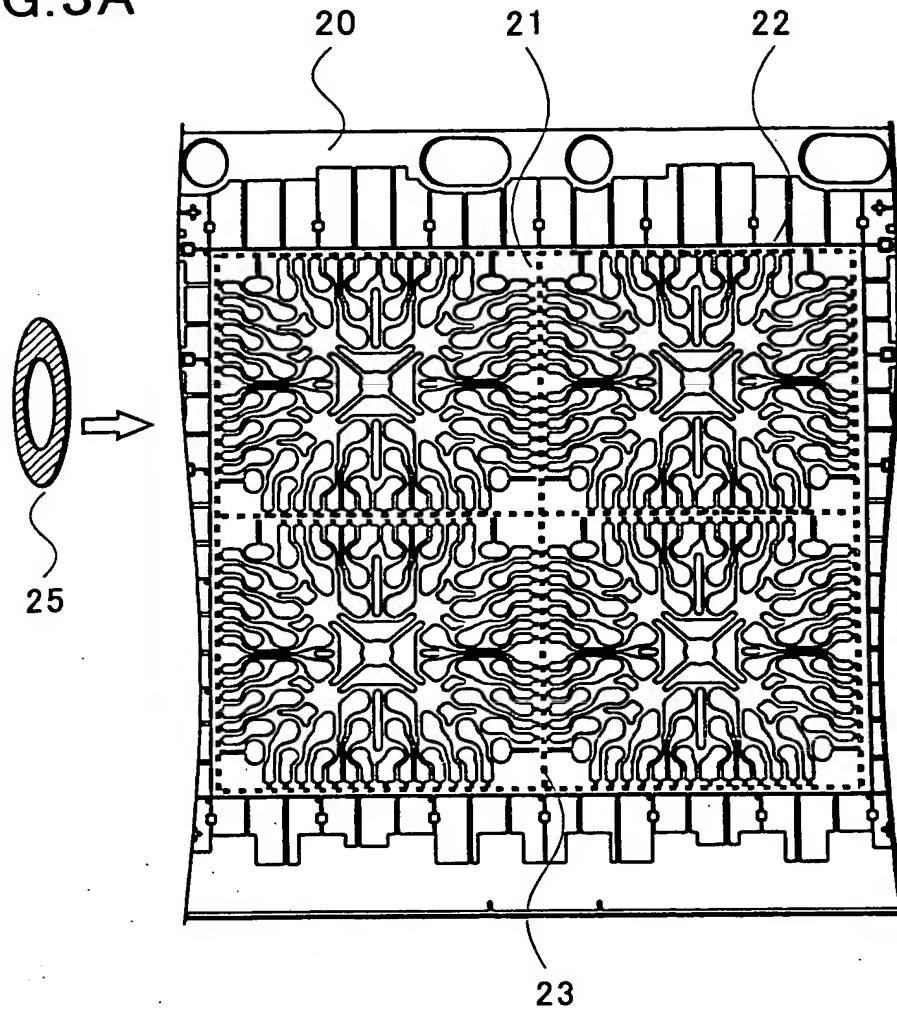


FIG. 3B

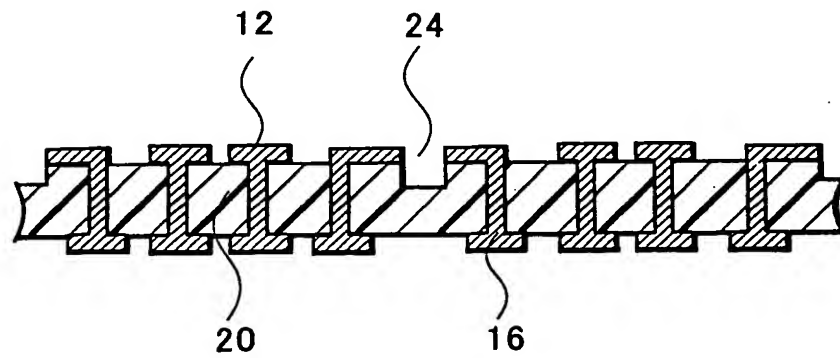


FIG.4

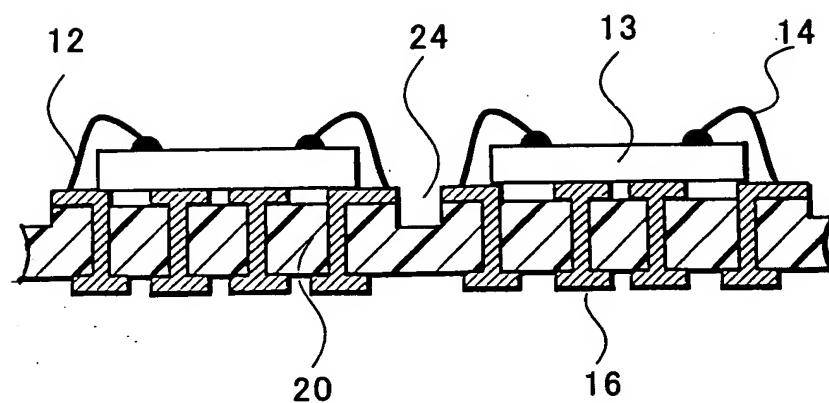


FIG.5

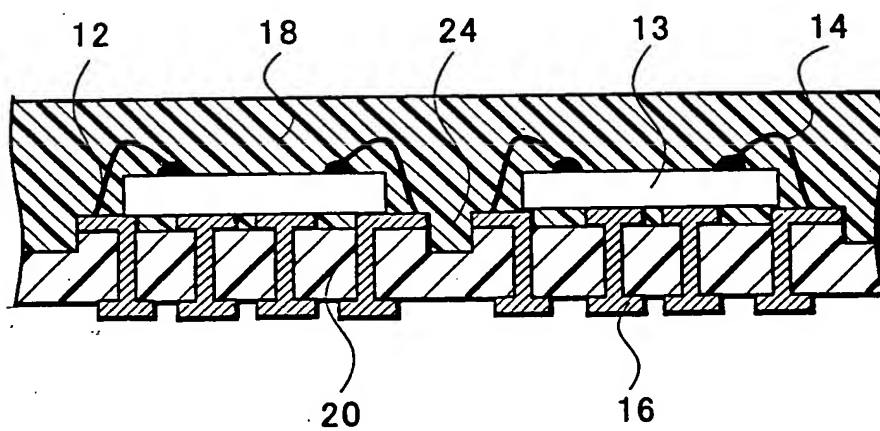


FIG.6

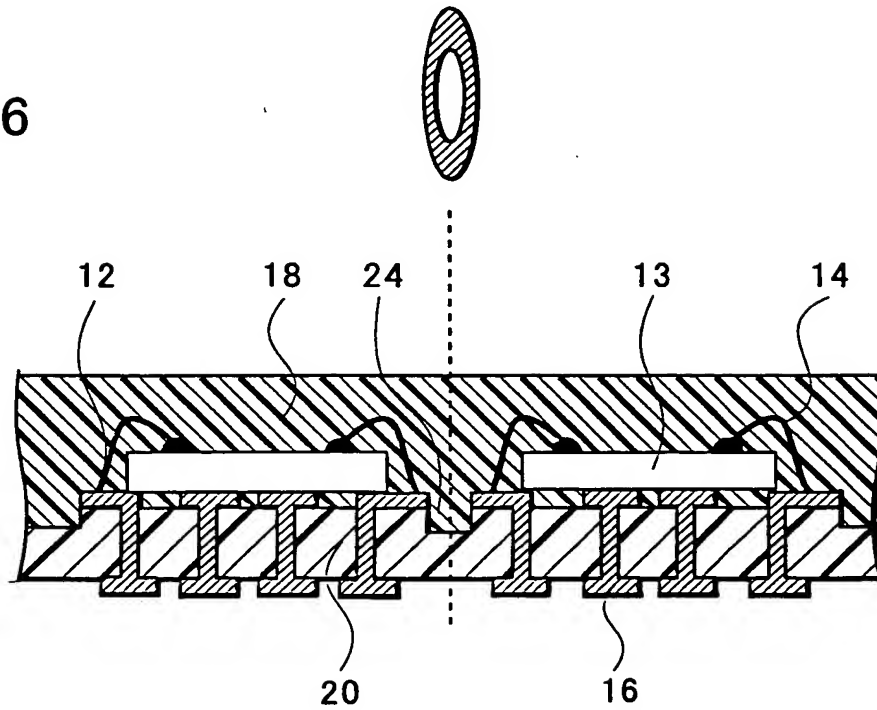


FIG.7

